

## 1. 2017 년 교육 계획

분기	차수	일시	내용	정원
1/4	31 차	2017.01.19	<u>Basic Course:</u> Microstructures Sample preparation for Metallurgy	20 명
	32 차	2017.02.09	<u>Basic Course:</u> Microstructures Sample preparation for Electronic Materials	20 명
	70 차	2017.03.09	<u>MultiPrep System Users Meeting:</u> Cross-Section/ TEM Wedge Sample Preparation	6 명
2/4	33 차	2017.04.13	<u>Basic Course:</u> Microstructures Sample preparation for Metallurgy	20 명
	34 차	2017.05.18	<u>Basic Course:</u> Microstructures Sample preparation for Electronic Materials	20 명
	71 차	2017.06.22	<u>MultiPrep System Users Meeting:</u> Parallel Thinning for Die & Package Analysis	6 명
3/4	35 차	2017.07.13	<u>Basic Course:</u> Microstructures Sample preparation for Metallurgy	20 명
	36 차	2017.08.24	<u>Basic Course:</u> Microstructures Sample preparation for Electronic Materials	20 명
	72 차	2017.09.14	<u>MultiPrep System Users Meeting:</u> Cross-Section/ TEM Wedge Sample Preparation	6 명
4/4	37 차	2017.10.19	<u>Basic Course:</u> Microstructures Sample preparation for Metallurgy	20 명
	38 차	2017.11.09	<u>Basic Course:</u> Microstructures Sample preparation for Electronic Materials	20 명
	73 차	2017.12.14	<u>MultiPrep System Users Meeting:</u> Parallel Thinning for Die & Package Analysis	6 명

## 2. 교육상세내역

### MultiPrep System

- 교육대상: MultiPrep System
- 교육참가비용: 10 만원/1 인 (단, 장비보유고객 1 인/1 회 무상)
- 교육참가인원: 선착순 6 명
- 강사: 센터장 및 담당연구원

#### 1. Cross-Section/TEM Wedge Sample Preparation

10:00AM~10:50AM	MultiPrep system application
11:00AM~11:50AM	Equipment Calibration 교육 및 실습
12:00PM~01:00PM	점심식사
01:15PM~02:40PM	Sample제작1(Cross-section)
03:00PM~06:00PM	Sample제작2(Wedge Cross-section)

#### 2. Parallel Thinning for Microelectronic device / SIMS sample preparation

10:00AM~10:50AM	MultiPrep system application
11:00AM~11:50AM	Equipment Calibration 교육 및 실습
12:00PM~01:00PM	점심식사
01:00PM~02:10PM	Sample제작1(Parallel Thinning / Sample preparation)
02:30PM~04:00PM	Sample제작2(Back-side Thinning / Thinning 실습)

### Basic Course

- 교육대상: 미세조직 관찰법을 배우려는 초보자(금속분야, 전자재료분야)
- 교육참가비용: 5 만원/1 인
- 교육참가인원: 선착순 20 명
- 강사: 센터장 및 담당연구원

#### 1. Microstructures Sample preparation for Electronic Materials

10:00AM~11:00AM	시편준비방법 및 관찰법
11:10AM~11:50AM	Sectioning 장비 작동법 및 실습
12:00PM~01:00PM	점심식사
01:15PM~02:15PM	Cold Mounting 실습
02:30PM~03:30PM	Polishing 실습 1
03:50PM~05:00PM	Polishing 실습 2

#### 2. Microstructures Sample preparation for Metallurgy

10:00AM~11:00AM	시편준비방법 및 관찰법
11:10AM~11:50AM	Sectioning 장비 작동법 및 실습
12:00PM~01:00PM	점심식사
01:15PM~02:15PM	Hot Mounting/Cold Mounting 실습
02:30PM~03:30PM	Polishing 및 관찰 실습 1
03:50PM~04:40PM	Polishing 및 관찰 실습 2